

PLATING BENCH

Individual tin/lead plating may be done on 32 wafers at a time. Touch-screen operator interface and programmed recipes allow ease of operation.

Each plating rack holds one six-inch wafer, and plates on one side. Racked wafers are rinsed in a centralized quick dump rinse bath. Plating solution is heated and filtered in the recirculating plating baths.



Each plating cell is connected to a separate rectifier, allowing precise plating control.



SEMI S2 Product Testing and Certification Available

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All specifications are subject to change without notice.



DIVISION OF LEATHERWOOD, INC.

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